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Polarization Detection of Deep-ultraviolet Light with Monoclinic Gallium Oxide Nanobelts

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S1. Screenshot of AFM measurement for the determination nanobelt thickness.

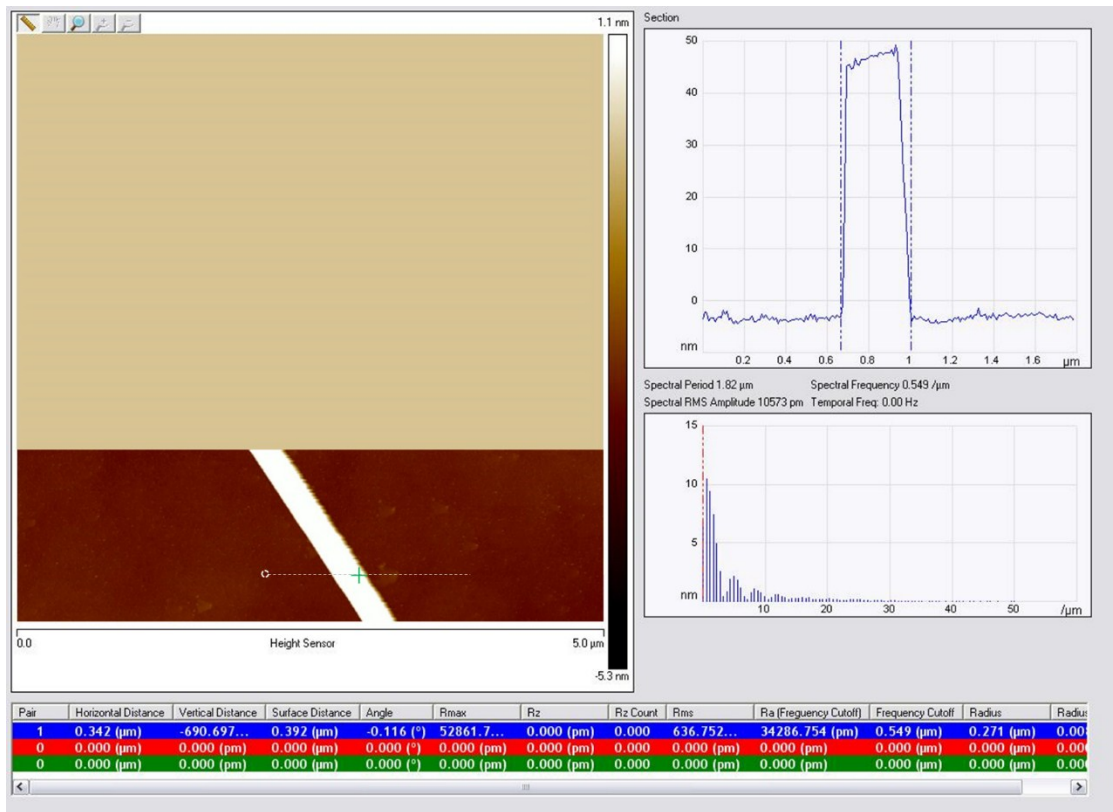


Figure S1 According to the AFM measurement, the thickness of a typical Ga₂O₃ nanobelt is around 50 nm and the width is approximately 280 nm. (The measurement was stopped before it was fully completed at that time, as the value of the thickness could be read out already.)

S2. HRTEM and FFT conducted at different spots on the nanobelt.

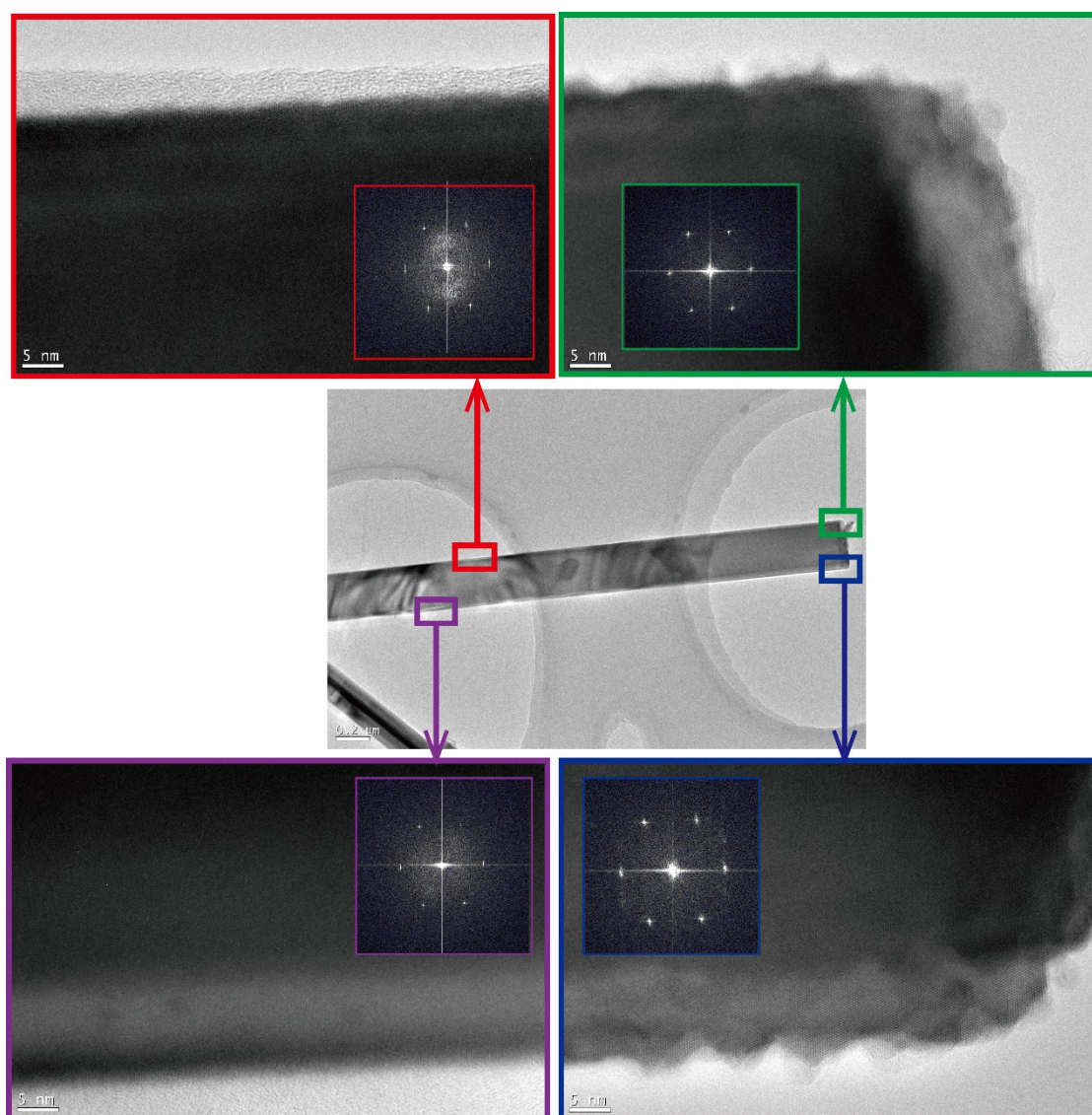


Figure S2 HRTEM and FFT conducted at different spots on the nanobelts. All the FFT show similar hexagonal patterns as in the SAED, indicating that most area of the nanobelt is single crystal.

S3. Photocurrent characteristics with various strain and the strain calculation method.

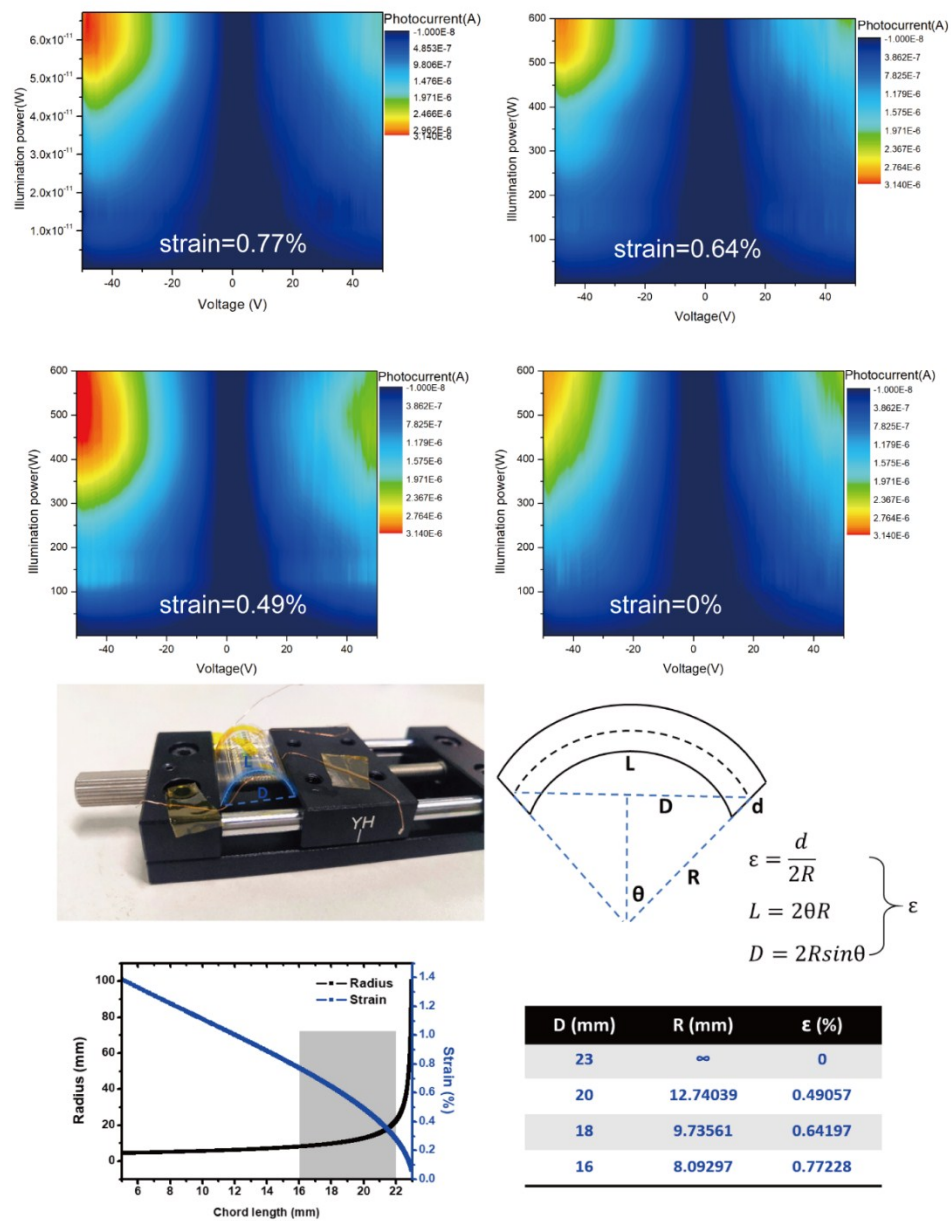


Figure S3 Photocurrent characteristics shows little difference with various tensile strain. The flexible device was bent with a clamp. The tensile strain can be acquired through the equations above, where ϵ is the strain, d is the substrate thickness, R is radius, D is chord length, L is arc length and θ is bending angle.

S4. FDTD simulation on Ga₂O₃ nanobelts with width ranging from 10 nm to 280 nm.

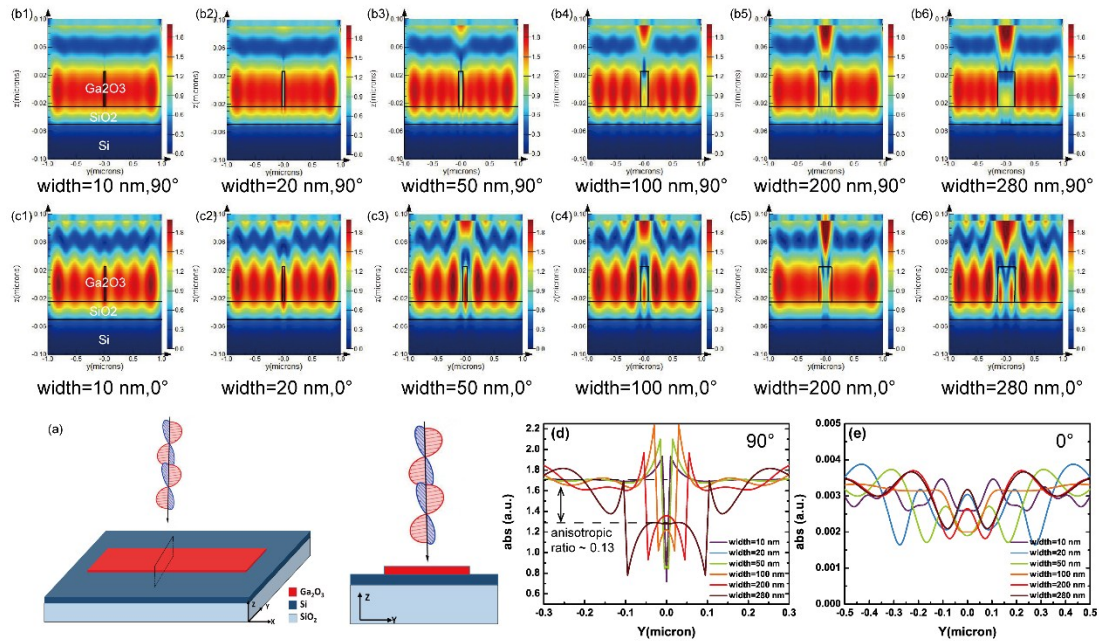


Figure S4 (a) Schematics of the FDTD simulation on Ga₂O₃ nanobelts on Si/SiO₂ substrate. (Similar anisotropic response is found in devices on Si/SiO₂ substrate, so the simulation result on Si/SiO₂ substrate also applies to device on PEN substrate.) (b1)–(b6) Simulation of photoelectric field with nanobelt width from 10 nm to 280 nm, radiated by 254 nm 90° polarized light (E//Y axis). (c1)–(c6) Simulation of photoelectric field with nanobelt width from 10 nm to 280 nm, radiated by 254 nm 0° polarized light (E//X axis). (d) The absorpition of 254 nm 90° polarized light (E//Y axis) within nanobelts of different width. It is obvious that the absorption was reduced more with narrower nanobelts. (e) The absorpition of 254 nm 0° polarized light (E//X axis) within nanobelts of different width. The absorption shows no obvious change with the nanobelts width.

The simulation is performed with lumerical FDTD solutions software. The refractive index of Ga₂O₃ is set to be 2 at 254 nm (according to C.V. Ramana, Properties of sputter-deposited gallium oxide, in: Gallium Oxide, Elsevier, 2019: pp. 47–66. <https://doi.org/10.1016/B978-0-12-814521-0.00003-8>).